



02/18/00

Docket No. 1945.P3 USA SILICON JB

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Box Patent Application  
 Assistant Commissioner for Patents  
 Washington, D.C. 20231

JC530 U.S. PTO  
 09/507629  
  
 02/18/00

Re. Inventor(s): Shen, et al.  
 Title: Self-Cleaning Process for Etching Silicon-Containing Material

Transmitted herewith is the patent application identified above, including:

- Specification, claims and abstract, totaling 27 pages.
- Drawings totaling 3 pages, X Formal   Informal.
- Executed Declaration and Power of Attorney.
- Information Disclosure Statement, PTO-1449 form, and copies of citations
- Assignment of the invention to Applied Materials, Inc., and Assignment Recordation Cover Sheet
- Post Card for return

FEE CALCULATION					
Fee Items	Claims Filed	Included with Basic Fee	Extra Claims	Fee Rate	Total
Total Claims	43	- 20 =	23	x 18.00	
Independent Claims	4	- 3 =	1	x 78.00	
Basic Filing Fee				690.00	
<b>TOTAL FEES</b>					<b>\$ 0.00</b>

- The Commissioner is hereby authorized to charge \$        to Deposit Account No. 50-1074
- The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 50-1074. A duplicate copy of this transmittal is enclosed.
- Please address all future correspondence to:

**APPLIED MATERIALS, INC.**  
**Patent Department**  
**P.O. Box 450A**  
**Santa Clara, CA 95052**

an envelope addressed to: Box Patent Applications, Patent and Trademark Office, Washington, D.C. 20231.

Express Mail Receipt No. EMS 242888218

Date of Deposit February 18, 2000

Ashok K. Janah  
 Registration No. 37,487